

DESIGN & PRODUCTION OF SILICON SENSORS FOR PHENIX MPC-EX

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(Yonsei Univ.)

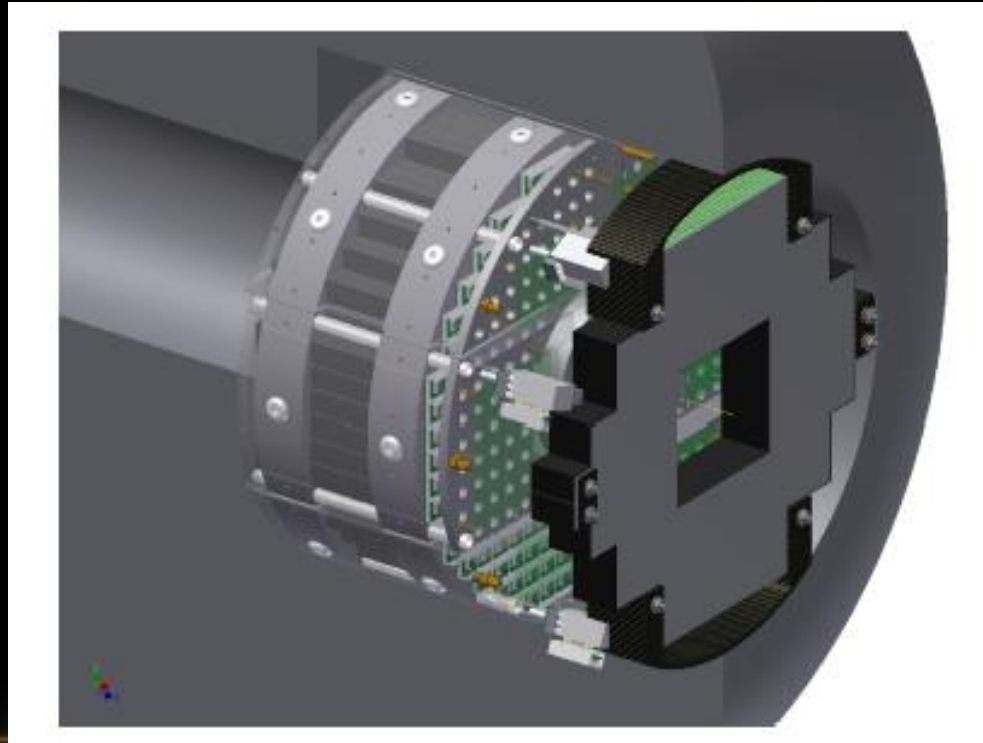
For PHENIX MPC-EX collaboration

MPC-EX

- 참여그룹
 - 국외 : Brookhaven Nation Laboratory, Iowa State University, University of California-Riverside, Los Alamos National Laboratory
 - 국내 : Yonsei University, ETRI, Ewha Womens University, Hanyang University, Chonbuk National University
- 발표관련 기여
 - Sensor design : BNL, Yonsei & ETRI
 - Sensor production : Yonsei & ETRI
 - Sensor test : Yonsei, Ewha Womens University

MPC-EX FOR PHENIX

- Application as a pre-shower for EMCAL (Electromagnetic calorimeter)



Electromagnetic Shower (A schematic view)

$\sim 1X_0 \times 20$

PAD

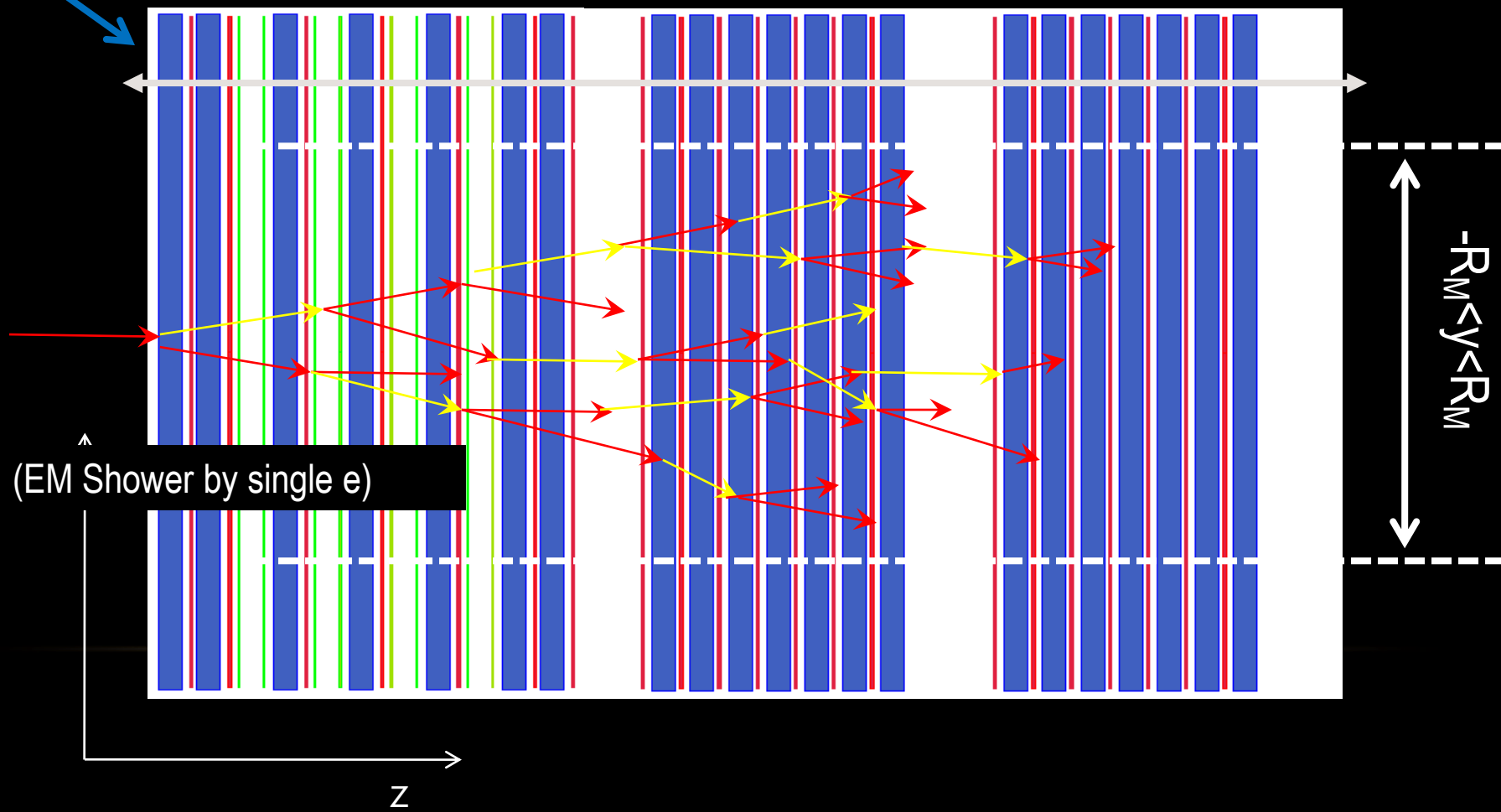
STRIP

W

SEG0

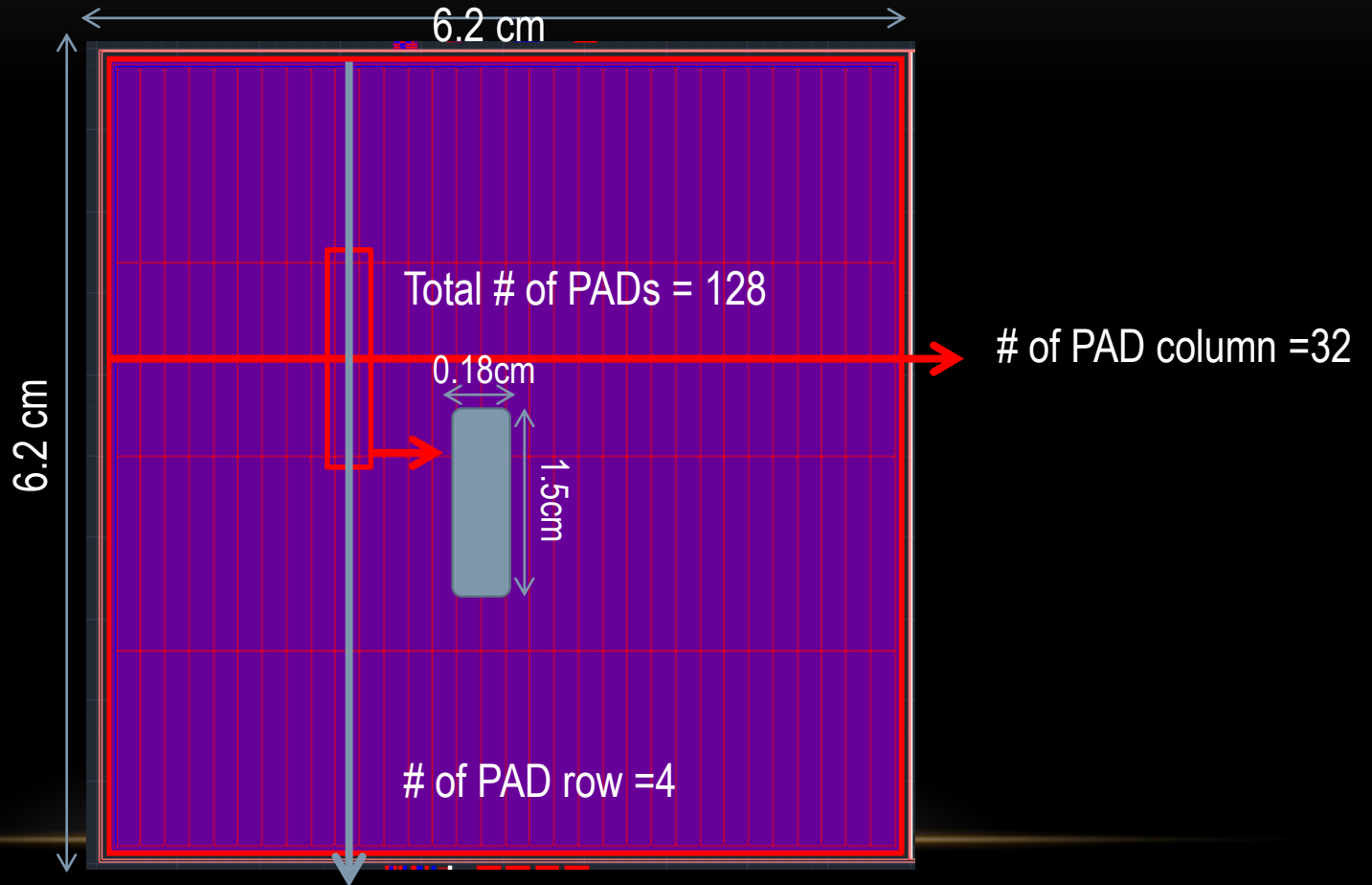
SEG1

SEG2

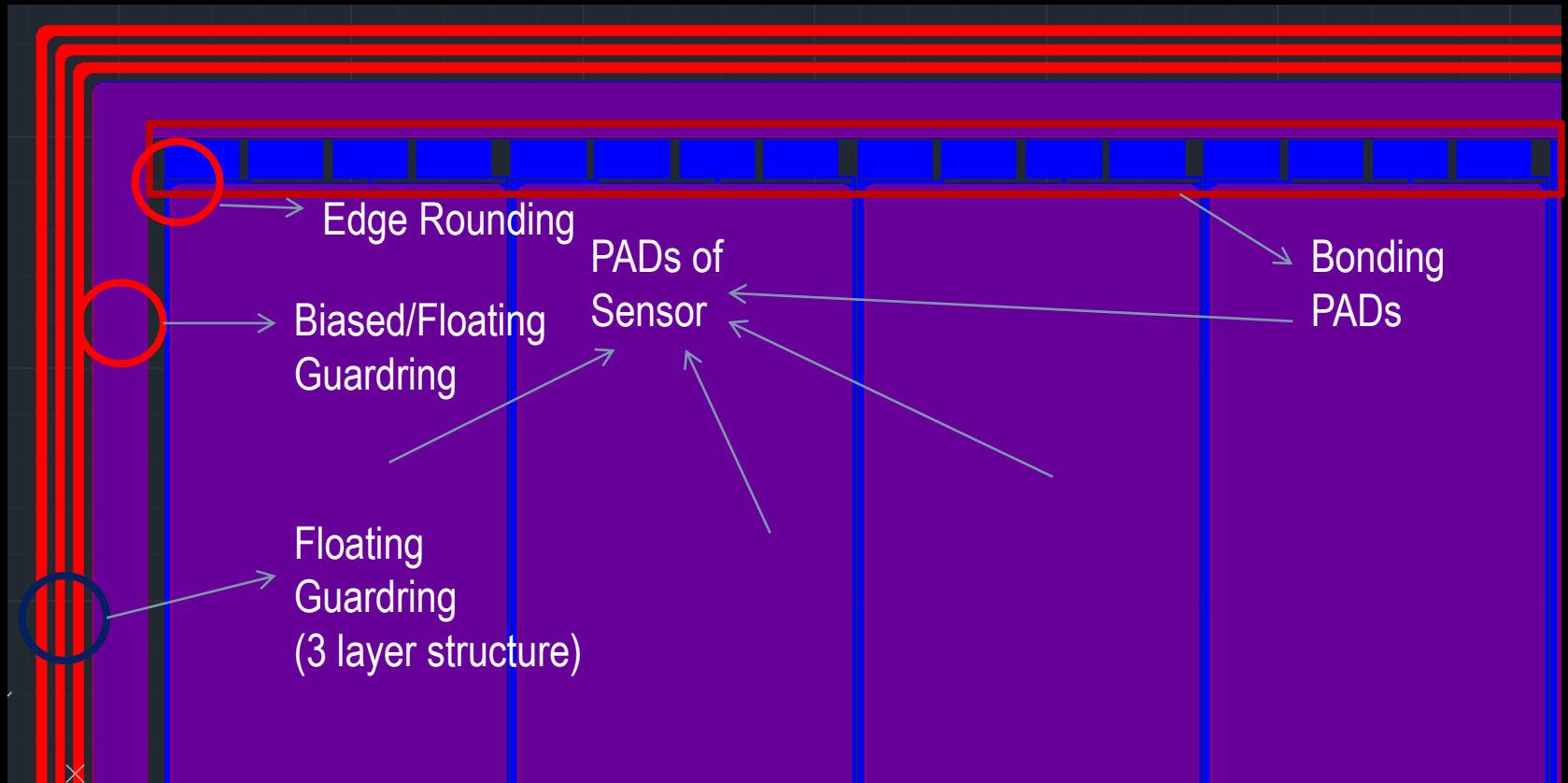


Sensor Design

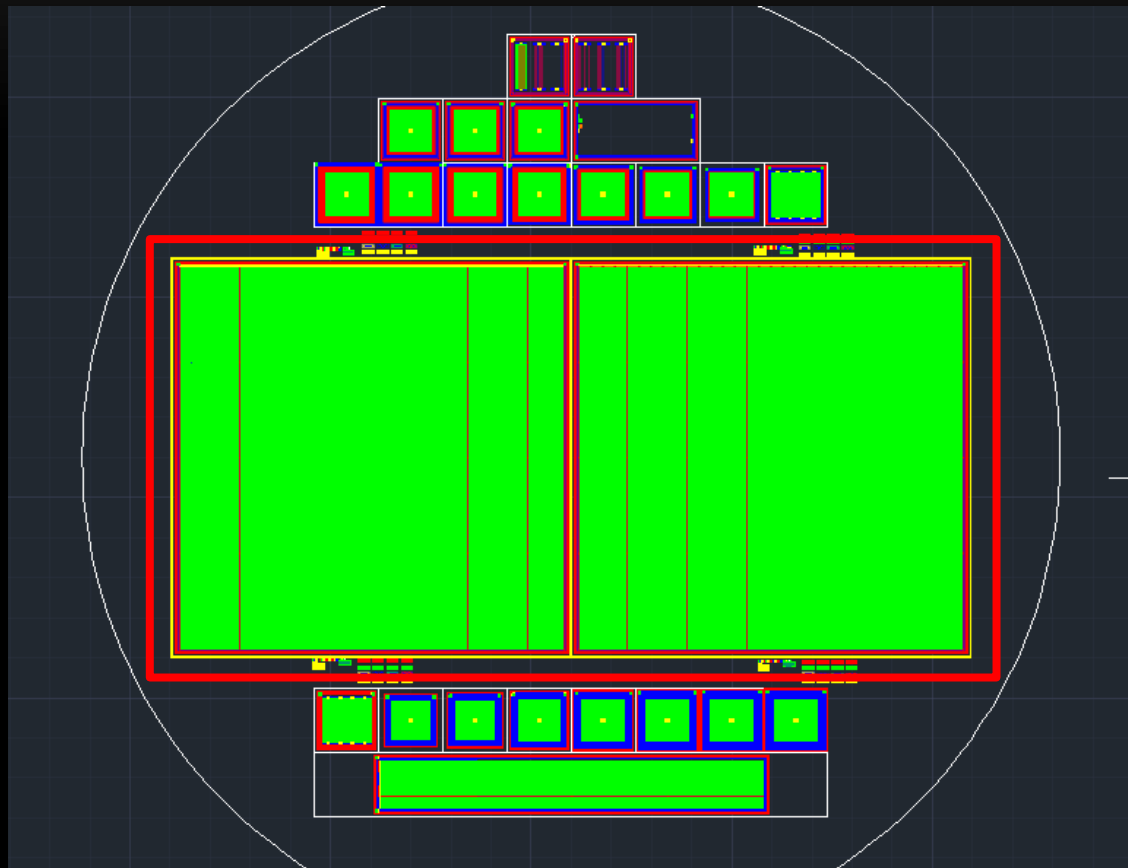
SENSOR GEOMETRY



SOME DESIGN DETAILS

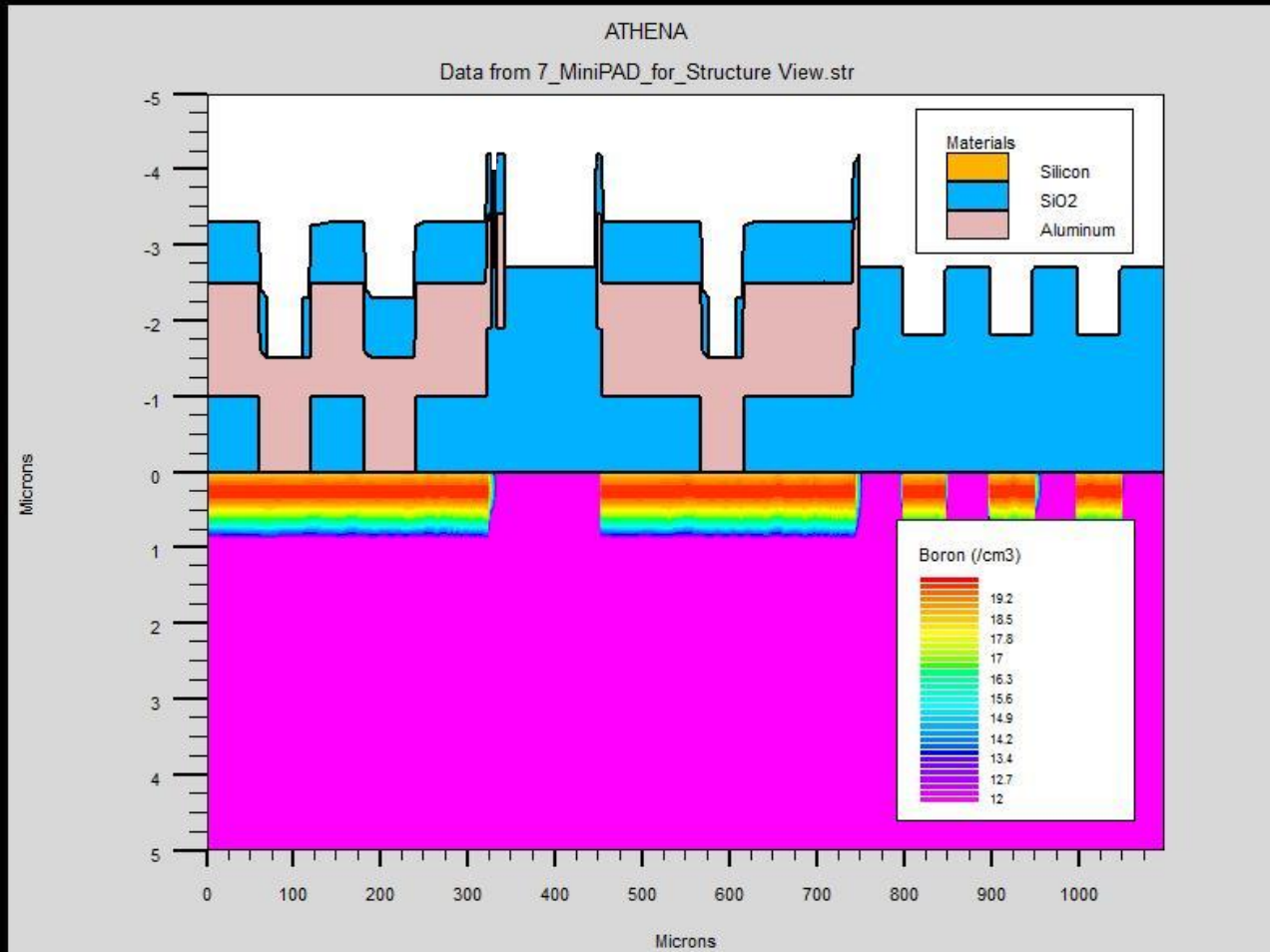


MASK DESIGN OF SILICON SENSOR



Production Mask

HOW DO WE MAKE IT? (CMOS PROCESS)



- Redraw
- Add Lyr
- All On
- All Off

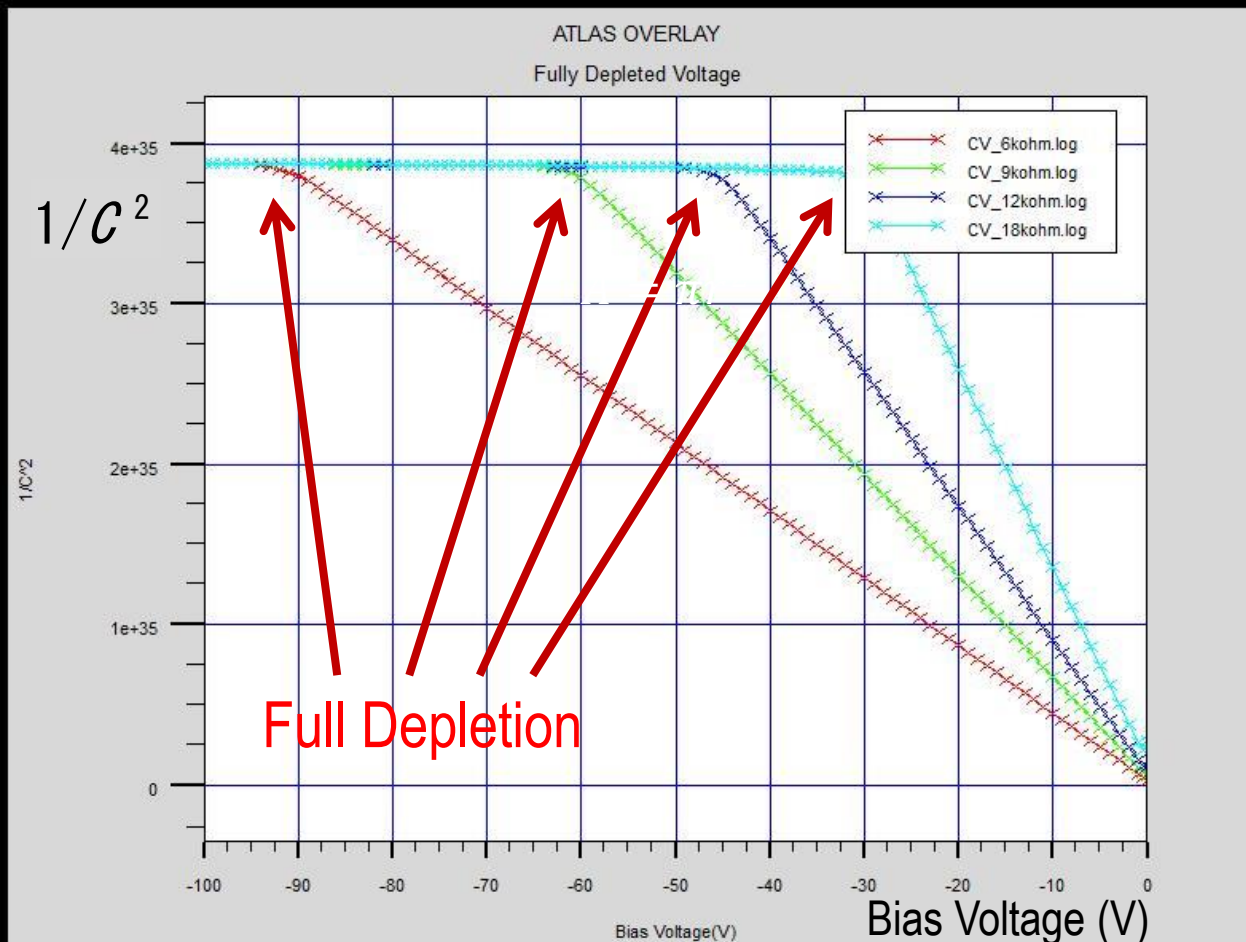
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Simulations

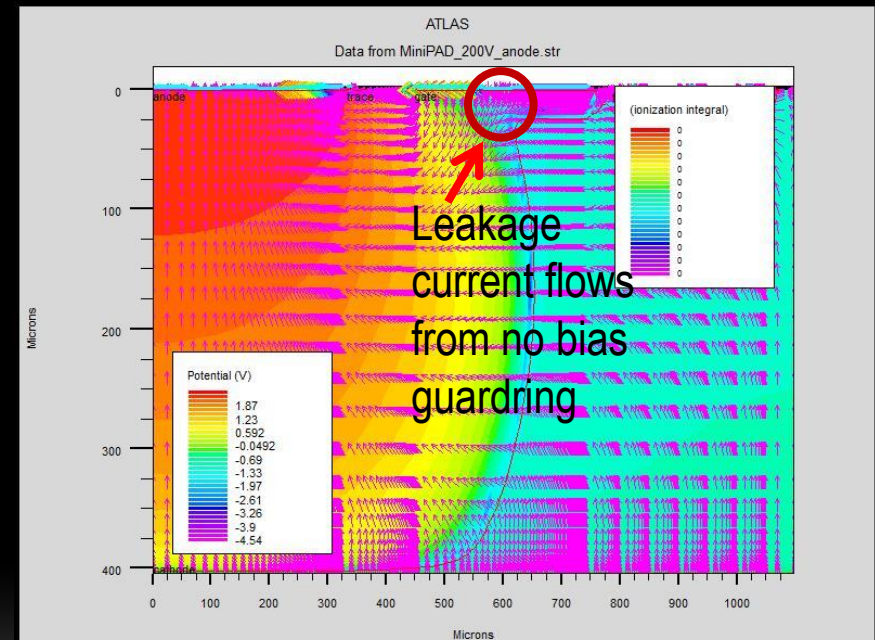
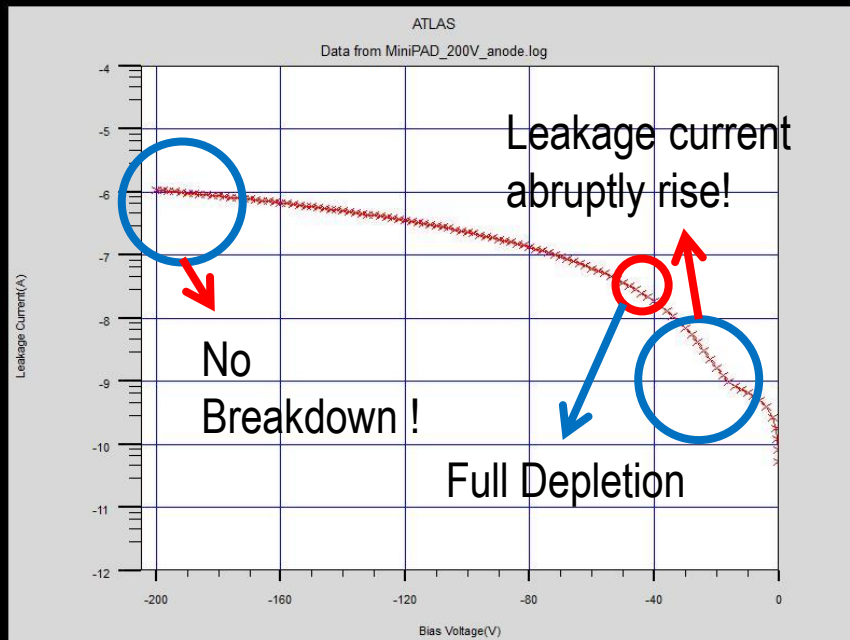
CAPACITANCE–VOLTAGE RELATION

- Wafer – Resistivity = 6, 9, 12, 18k Ω ·cm / Thickness = 405 μ m, Orientation = <100>
- Full Depletion Voltage = 90V(6k Ω ·cm), 60V(9k Ω ·cm), 45V(12k Ω ·cm), 30V(18k Ω ·cm)



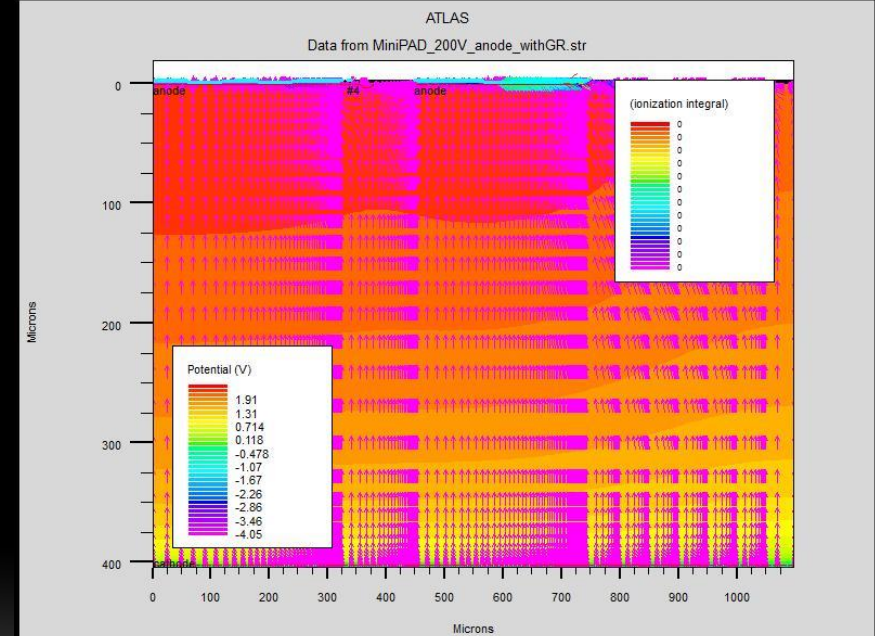
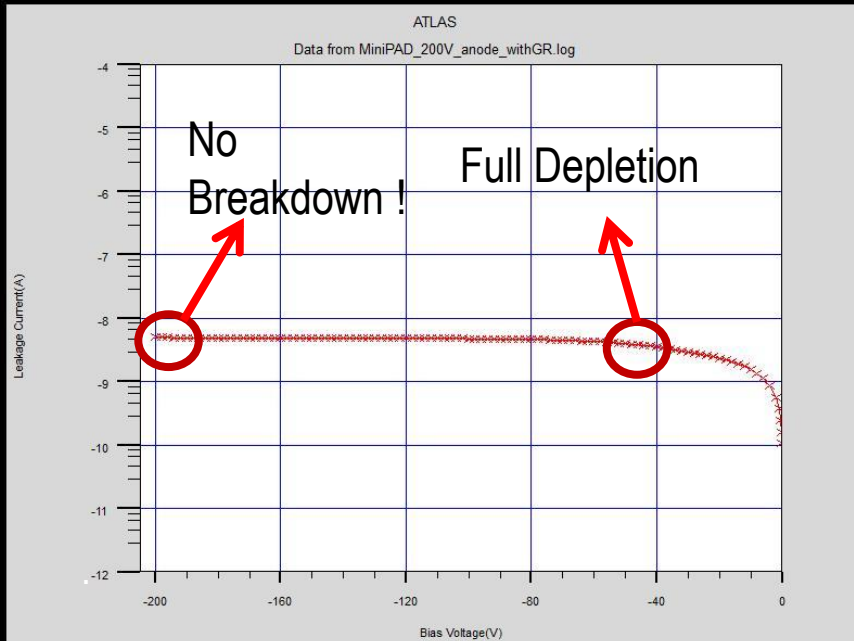
CURRENT-VOLTAGE RELATION (ONGOING WORK)

- No breakdown upto 200V but somewhat large leakage current



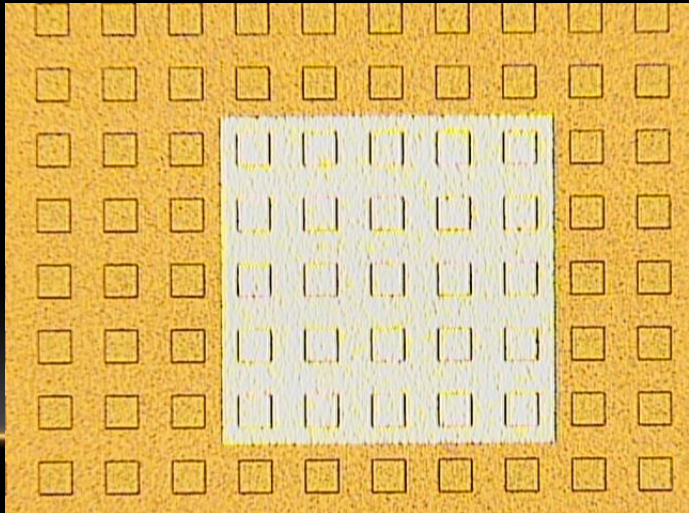
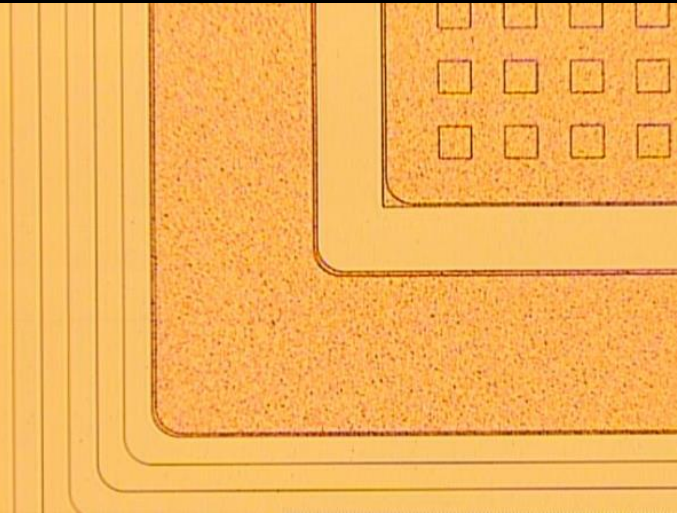
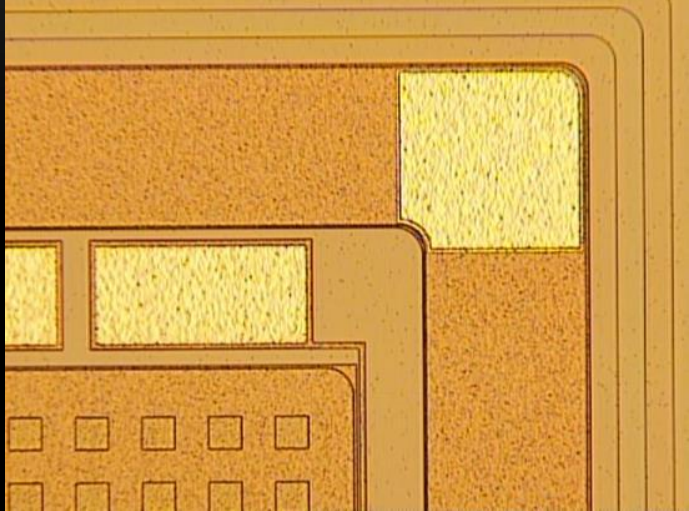
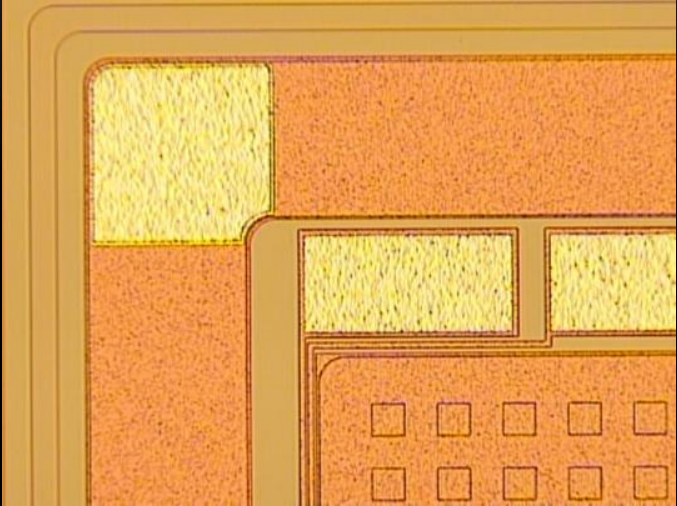
CURRENT-VOLTAGE RELATION (ONGOING WORK)

- No breakdown upto 200V and reduced leakage current

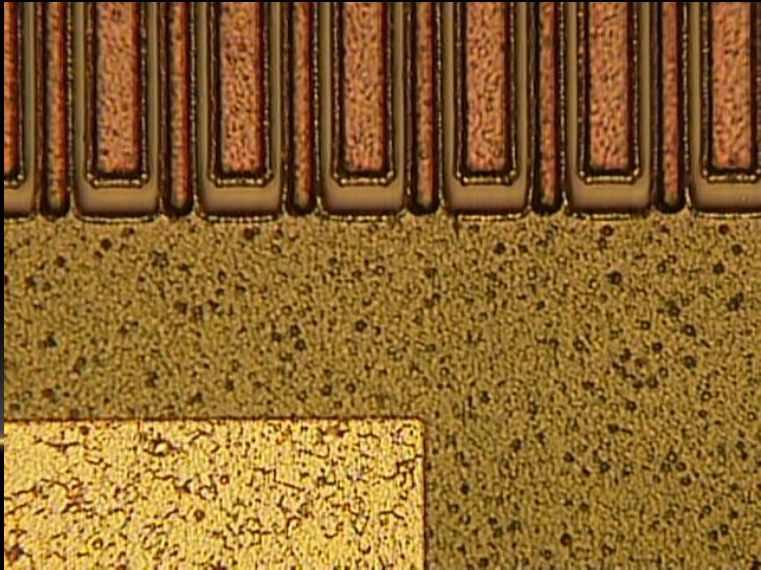
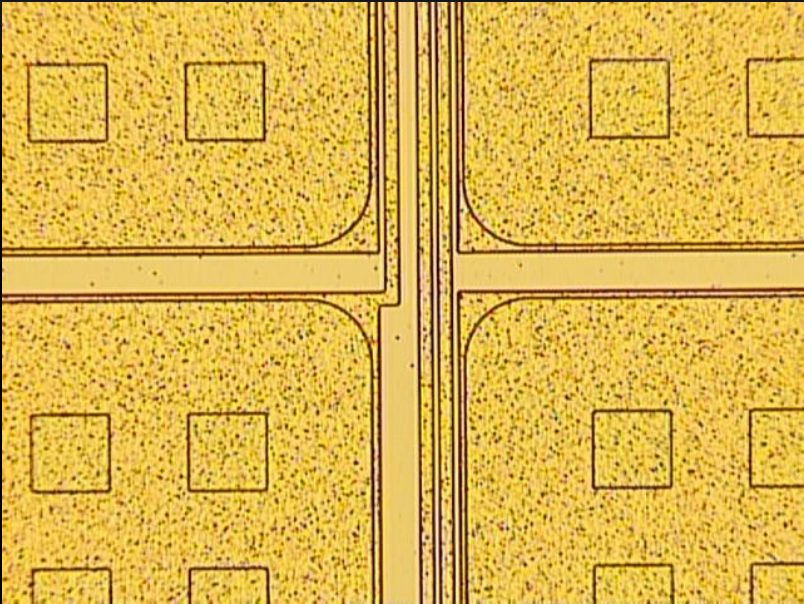


Fabrication Monitoring

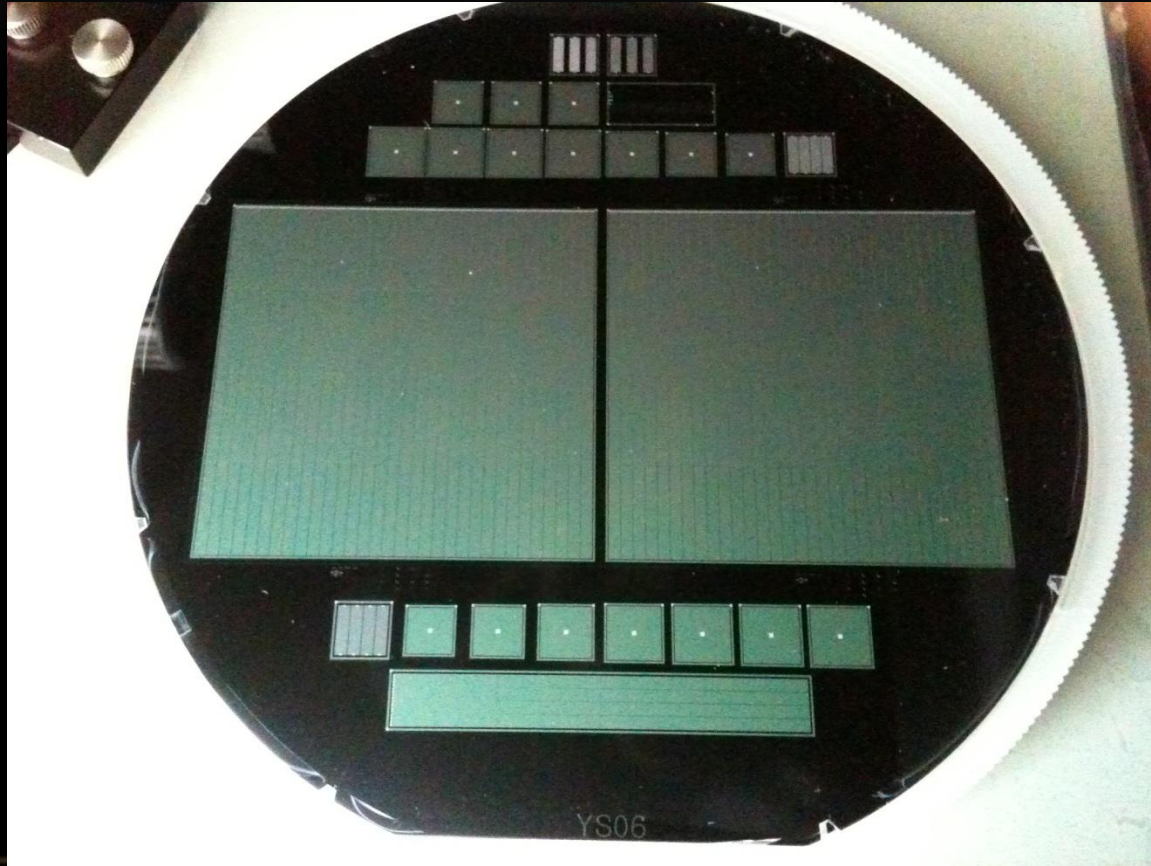
ALIGNMENT



ALIGNMENT



완성된 WAFER 사진



SUMMARY

- MPC-EX is a pre-shower detector in Si/W sandwich structure.
- We designed and fabricated a prototype of the relevant Si sensor.